ISPlasma/IC-PLANTS is a specialized international symposium that brings together about 1,000 world-leading scientists and engineers in Nagoya, Japan to discuss latest researches in the fields of advanced plasma science, its applications for processing and manufacturing of nitrides and nanomaterials, as well as new systems for technology transfers. This symposium will address issues such as global warming, resources and energy problems to which advanced plasma science and its application technologies can greatly contribute. In this symposium biosensing technologies will be also highlighted, because of their increasing importance in healthcare, agri-food and environmental areas. We hope that this symposium will provide an ideal venue for the exchange of new ideas and information, and also support the initiation or further development of international collaborations among those who work in these multidisciplinary fields.

**Related Fields**

- Plasma Science & Technologies
  - Plasma Source
  - Plasma in Liquid
  - Flexible Electronics
  - Modeling & Simulation
  - Etching Process
- Nitride Semiconductors
  - Crystal Growth of GaN & Related Materials
  - Device Processing
  - MBE Growth & Nitrogen Source
  - Optical & Optoelectronic Devices
- Nanomaterials
  - Nanodots & Nanoparticles
  - 2D Materials
  - Composites & Functionally Graded Materials
  - Surface Modification & Functionalization
- Applications for Energy & Environment
  - Plasma for Nano & Green Technologies
- Flexible Electronics
- Plasma for Nano & Green Technologies
- Plasma for Nano & Green Technologies
  - Plasma for Nano & Green Technologies

**Bio Applications**

- Plasma Biology & Medicine
  - Biomaterials
  - Bioimaging
  - Biosensors
  - Characterization
  - Electron & Power Devices
- Nanotubes, Nanowires & Nanorods
- Porous Materials & Membranes
- Surface Modification & Functionalization
- Nanomedicine & Sensing
- Biodevices, uTAS, Lab on a Chip
- Device Fabrication Technologies

**Abstract Submission**

Online abstract submission (one-page English) is available from [http://www.isplasma.jp/](http://www.isplasma.jp/). Submission Deadline: Friday, October 16, 2020 JST

**Special Issue**

Selected papers will be published in a special issue of a scientific journal.

**Tutorial**

Tutorial for Plasma Science, Nitride Semiconductors, Nanomaterials, and Bio Applications will be held.

**Contact**

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E-mail: isplasma2021@intergroup.co.jp  
Website: [http://www.isplasma.jp/](http://www.isplasma.jp/)
**Program**

**Plenary Speakers**
A. Yoshino (Meijo University, Asahi Kasei Corp., JAPAN)

**Keynote Speakers**
J.P. Booth (CNRS at LPP, FRANCE)
M. Fujii (Kobe University, JAPAN)
T. Kachi (Nagoya University, JAPAN)
S. Toyokuni (Nagoya University, JAPAN)

**Invited Speakers**
P. J. Bruggeman (University of Minnesota, USA)
D. Boonyawan (Chiang Mai University, THAILAND)
E. H. Choi (Kwangoon University, KOREA)
S. Graham (Georgia Institute of Technology, USA)
M. Hori (Nagoya University, JAPAN)
K. Ide (Tokyo Institute of Technology, JAPAN)
T. Kaneko (Tohoku University, JAPAN)
M. Keidar (The George Washington University, USA)
A. Kohno (Fukuoka University, JAPAN)
Y. Koide (National Institute for Materials Science, JAPAN)
S. Konstantinidis (University of Mons, BELGIUM)
J. S. Kwon (Yonsei University College of Dentistry, KOREA)
Y. Lin (National Synchrotron Radiation Research Center, TAIWAN)
B. Locke (Florida State University, USA)

**Tutorial Speakers**
T. P. Chow (Rensselaer Polytechnic Institute, USA)
U. Czarnetzki (Rhur-Universitat Bochum, GERMANY)
D. Graves (UC Berkle, USA)
L. Miao (Guilin University of Electronic Technology, CHINA)